

[DLP9000](http://www.ti.com.cn/product/cn/dlp9000?qgpn=dlp9000)

ZHCSD19A –SEPTEMBER 2014–REVISED OCTOBER 2015

Support & [Community](http://www.ti.com.cn/product/cn/DLP9000?dcmp=dsproject&hqs=support&#community)

으리

DLP9000 系列 **0.9 WQXGA A** 型 **DMD**

Technical [Documents](http://www.ti.com.cn/product/cn/DLP9000?dcmp=dsproject&hqs=td&#doctype2)

1 特性

- 高分辨率 2560×1600 (WQXGA) 阵列
	- 超过四百万个微镜
	- 7.56µm 微镜间距
	- 0.9 英寸微镜阵列对角线
	- ±12°微镜倾斜角(相对于平板状态)
	- 设计用于边缘照明
	- 集成微镜驱动器电路
	- 两个高速选项
- • 采用 DLPC910 控制器的 DLP9000XFLS
	- 480Mhz 输入数据时钟速率
	- 对于持续输入数据流,最高像素数据速率大于 61 千兆位/秒
	- 1 位二进制模式速率达 15kHz
	- 采用调制照明的 8 位灰度模式, 速率达 1.8kHz
	- 采用两个 DLPC900 控制器的 DLP9000FLS
		- 400Mhz 输入数据时钟速率
		- 最高像素数据速率大于 38 千兆位/秒, 多达 400 个预存储的二进制模式
		- 1 位二进制模式速率达 9.5kHz
	- 8 位灰度模式速率达 247Hz
- • 设计用于宽波长范围
	- 400nm 至 700nm
	- 窗口传输效率 95%(单通、通过双窗面)
	- 微镜反射率 88%
	- 阵列衍射效率 86%
	- 阵列填充因子 92%

2 应用

- 工业
	- 机器视觉和质量控制
	- 3D 打印
	- 直接成像平版印刷术
	- 激光打标和修复

Tools & **[Software](http://www.ti.com.cn/product/cn/DLP9000?dcmp=dsproject&hqs=sw&#desKit)**

- 医疗
	- 眼科
	- 针对四肢和皮肤测量的 3D 扫描仪
	- 高光谱成像
	- 高光谱扫描
- 显示屏
	- 3D 成像显微镜
	- 智能和自适应照明

3 说明

高分辨率 DLP9000FLS 和 DLP9000XFLS 数字微镜器 件 (DMD) 是可调制入射光幅度、方向和/或相位的空间 照明调制器 (SLM), 微镜数超过四百万。这种高级照 明控制技术 适用于 工业、医疗和消费品市场中的许多 应用。DLP9000XFLS 自身具备的流传输性质与其 DLPC910 控制器相结合,可为平版印刷应用提供超高 速持续 数据流。这两款 DMD 能够为 3D 打印应用实 现更大的构造尺寸和更为精细的 分辨率。高分辨率支 持扫描较大物体,这对于 3D 机器视觉应用有直接的 帮助。

(1) 要了解所有可用封装,请见数据表末尾的可订购产品附录。

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目录

4 修订历史记录

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注:之前版本的页码可能与当前版本有所不同。

Changes from Original (September 2014) to Revision A Page

5 Description (continued)

Reliable function and operation of the DLP9000 family requires that each DMD be used in conjunction with its specific digital controller. The DLP9000XFLS must be driven by a single DLPC910 Controller and the DLP9000FLS must be driven by two DLPC900 Controllers. These dedicated chipsets provide robust, high resolution, high speed system solutions.

6 Pin Configuration and Functions

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NSTRUMENTS

EXAS

(1) The following power supplies are required to operate the DMD: VCC, VCCI, VOFFSET, VBIAS, and VRESET. VSS must also be connected.

(2) DDR = Double Data Rate. SDR = Single Data Rate. Refer to the *Timing [Requirements](#page-13-0)* regarding specifications and relationships.

(3) Internal term = CMOS level internal termination. Refer to *[Recommended](#page-10-2) Operating Conditions* regarding differential termination specification.

(4) Dielectric Constant for the DMD Type A ceramic package is approximately 9.6. For the package trace lengths shown: Propagation Speed = $11.8 / \sqrt{9.6} = 3.808 \text{ in/ns}.$ Propagation Delay = 0.262 ns/in = 262 ps/in = 10.315 ps/mm.

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connected.

Pin Functions

(I/O/P) SIGNAL DESCRIPTION

VOFFSET | U1 | W1 | Power Analog Supply voltage for stepped high voltage at Micromirror address electrodes.

VBIAS A3 A5 A7 Power Analog Supply voltage for positive Bias level of Micromirror reset signal. VBIAS A9 A11 B2 Power Analog Supply voltage for positive Bias level of Micromirror reset signal.

VRESET | L31 | N31 | R31 | Power | Analog | Supply voltage for negative Reset level of Micromirror reset signal. VRESET | U31 | W31 | AA31 | Power | Analog | Supply voltage for negative Reset level of Micromirror reset signal.

VCC AE31 AG1 AG31 Power Analog Supply voltage for normal high level at Micromirror address electrodes.

PIN TYPE

VCC A21 A23 A25 Power Analog VCC | A27 | A29 | C1 | Power | Analog VCC C31 E31 G31 Power Analog

VCC AJ31 AK2 AK30 Power Analog VCC AL3 AL5 AL7 Power Analog VCC AL21 AL23 AL25 Power Analog VCC | AL27 | | Power | Analog

VOFFSET | L1 | N1 | R1 | Power | Analog | Supply voltage for HVCMOS logic.

VCC | J31 | K2 | AC31 | Power | Analog | Supply voltage for LVCMOS core logic.

VCCI | H18 | H24 | M6 | Power | Analog | Supply voltage for LVDS receivers. VCCI M26 P6 P26 Power Analog Supply voltage for LVDS receivers.

VOFFSET | AC1 | AA1 Power Analog Supply voltage for Offset level of MBRST(31:0).

NAME (1) NO. NO. NO.

(1) The following power supplies are required to operate the DMD: VCC, VCCI, VOFFSET, VBIAS, and VRESET. VSS must also be

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7 Specifications

7.1 Absolute Maximum Ratings

over operating free-air temperature range (unless otherwise noted)⁽¹⁾

(1) Stresses beyond those listed under *Absolute Maximum Ratings* may cause permanent damage to the device. These are stress ratings only, and functional operation of the device is not implied at these or any other conditions beyond those indicated under *[Recommended](#page-10-2) Operating [Conditions](#page-10-2)*. Exposure above *[Recommended](#page-10-2) Operating Conditions* for extended periods may affect device reliability.

(2) All voltages are referenced to common ground VSS. Supply voltages VCC, VCCI, VOFFSET, VBIAS, and VRESET are all required for proper DMD operation. VSS must also be connected

(3) VOFFSET supply transients must fall within specified voltages.

(4) To prevent excess current, the supply voltage delta |VCCI – VCC| must be less than specified limit.

(5) To prevent excess current, the supply voltage delta |VBIAS – VOFFSET| must be less than specified limit. Refer to *Power [Supply](#page-37-0) [Recommendations](#page-37-0)* for additional information.

(6) This maximum LVDS input voltage rating applies when each input of a differential pair is at the same voltage potential.

(7) LVDS differential inputs must not exceed the specified limit or damage may result to the internal termination resistors.

(8) Exposure of the DMD simultaneously to any combination of the maximum operating conditions for case temperature, differential temperature, or illumination power density may affect device reliability.

(9) DMD Temperature is the worst-case of any test point shown in [Figure](#page-30-1) 15, or the active array as calculated by the *[Micromirror](#page-30-0) Array [Temperature](#page-30-0) Calculation*.

7.2 Storage Conditions

applicable before the DMD is installed in the final product

7.3 ESD Ratings

(1) JEDEC document JEP155 states that 500-V HBM allows safe manufacturing with a standard ESD control process.

7.4 Recommended Operating Conditions

over operating free-air temperature range (unless otherwise noted)

(1) Supply voltages VCC, VCCI, VOFFSET, VBIAS, and VRESET are all required for proper DMD operation. VSS must also be connected.

(2) All voltages are referenced to common ground VSS.

(3) VOFFSET supply transients must fall within specified max voltages.

(4) To prevent excess current, the supply voltage delta |VCCI – VCC| must be less than specified limit.

(5) To prevent excess current, the supply voltage delta |VBIAS – VOFFSET| must be less than specified limit. Refer to *Power [Supply](#page-37-0) [Recommendations](#page-37-0)* for additional information.

(6) Tester Conditions for V_{IH} and V_{IL} : Frequency = 60MHz. Maximum Rise Time = 2.5 ns at (20% to 80%) Frequency = 60MHz. Maximum Fall Time = 2.5 ns at (80% to 20%)

(7) PWRDNZ input pin resets the SCP and disables the LVDS receivers. PWRDNZ input pin overrides SCPENZ input pin and tri-states the SCPDO output pin.

(8) The SCP clock is a gated clock. Duty cycle shall be 50% ± 10%. SCP parameter is related to the frequency of DCLK.

(9) Refer to [Figure](#page-15-0) 1.

(10) SCP internal oscillator is specified to operate all SCP registers. For all SCP operations, DCLK is required.

Recommended Operating Conditions (continued)

over operating free-air temperature range (unless otherwise noted)

(11) The DLP9000X, coupled with the DLPC910, is designed for operation at 2 specific DCLK frequencies only - 400Mhz or 480Mhz. 480Mhz operation is only allowed at the specific environmental operating conditions as shown in this table.

(12) Refer to [Figure](#page-15-1) 2, [Figure](#page-16-0) 3, and [Figure](#page-16-1) 4.

(13) Optimal, long-term performance and optical efficiency of the Digital Micromirror Device (DMD) can be affected by various application parameters, including illumination spectrum, illumination power density, micromirror landed duty-cycle, ambient temperature (storage and operating), DMD temperature, ambient humidity (storage and operating), and power on or off duty cycle. TI recommends that application-specific effects be considered as early as possible in the design cycle.

(14) DMD Temperature is the worst-case of any thermal test point in [Figure](#page-30-1) 15, or the active array as calculated by the *[Micromirror](#page-30-0) Array [Temperature](#page-30-0) Calculation*.

(15) Per [Figure](#page-32-0) 16, the maximum operational case temperature should be derated based on the micromirror landed duty cycle that the DMD experiences in the end application. Refer to *Micromirror [Landed-On/Landed-Off](#page-31-0) Duty Cycle* for a definition of micromirror landed duty cycle.

(16) For the DLP9000XFLS, [Figure](#page-32-0) 16 does not apply and the maximum temperature is as specified in table.

(17) As measured between any two points on the exterior of the package, or as predicted between any two points inside the micromirror array cavity. Refer to *Thermal [Information](#page-12-0)* and *Micromirror Array [Temperature](#page-30-0) Calculation*.

(18) Refer to *Thermal [Information](#page-12-0)* and *Micromirror Array [Temperature](#page-30-0) Calculation*.

7.5 Thermal Information

(1) The DMD is designed to conduct absorbed and dissipated heat to the back of the package where it can be removed by an appropriate heat sink. The heat sink and cooling system must be capable of maintaining the package within the temperature range specified in the *[Recommended](#page-10-2) Operating Conditions*. The total heat load on the DMD is largely driven by the incident light absorbed by the active area; although other contributions include light energy absorbed by the window aperture and electrical power dissipation of the array. Optical systems should be designed to minimize the light energy falling outside the window clear aperture since any additional thermal load in this area can significantly degrade the reliability of the device. .

7.6 Electrical Characteristics

over operating free-air temperature range (unless otherwise noted)

(1) All voltages are referenced to common ground VSS. Supply voltages VCC, VCCI, VOFFSET, VBIAS, and VRESET are all required for proper DMD operation. VSS must also be connected.

(2) Applies to LVCMOS input pins only. Does not apply to LVDS pins and MBRST pins.
(3) LVCMOS input pins utilize an internal 18000 Ω passive resistor for pull-up and pull-d

(3) LVCMOS input pins utilize an internal 18000 Ω passive resistor for pull-up and pull-down configurations. Refer to *Pin [Configuration](#page-2-1) and [Functions](#page-2-1)* to determine pull-up or pull-down configuration used.

(4) To prevent excess current, the supply voltage delta |VCCI – VCC| must be less than specified limit.

(5) To prevent excess current, the supply voltage delta |VBIAS – VOFFSET| must be less than specified limit.

(6) Total power on the active micromirror array is the sum of the electrical power dissipation and the absorbed power from the illumination source. See the *Micromirror Array [Temperature](#page-30-0) Calculation*.

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7.7 Timing Requirements

over *[Recommended](#page-10-2) Operating Conditions* (unless otherwise noted) (1)

- (1) Refer to *Pin [Configuration](#page-2-1) and Functions* for pin details.
- (2) Refer to [Figure](#page-16-2) 5.
- (3) Refer to [Figure](#page-17-0) 6.
- (4) Refer to [Figure](#page-17-0) 6.

Timing Requirements (continued)

over *[Recommended](#page-10-2) Operating Conditions* (unless otherwise noted) [\(1\)](#page-14-0)

(5) Refer to [Figure](#page-17-1) 7.

Not to scale.

Refer to SCP Interface section of the Recommended Operating Conditions table.

Refer to LVDS Interface section of the Recommended Operating Conditions table. Refer to Pin Configuration and Functions for list of LVDS pins.

Figure 2. LVDS Voltage Definitions (References)

Not to scale.

Refer to LVDS Interface section of the Recommended Operating Conditions table.

Figure 3. LVDS Voltage Parameters

Refer to LVDS Interface section of the Recommended Operating Conditions table. Refer to Pin Configuration and Functions for list of LVDS pins.

Figure 5. Rise Time and Fall Time

Not to scale.

Refer to LVDS INTERFACE section in the Timing Requirements table.

Not to scale.

Refer to LVDS INTERFACE section in the Timing Requirements table.

7.8 Capacitance at Recommended Operating Conditions

over operating free-air temperature range (unless otherwise noted)

7.9 Typical Characteristics

The DLP9000FLS DMD is controlled by two DLPC900 controllers. This chipset offers two modes of operation. The first is Video mode where the video source is displayed on the DMD. The second is Pattern mode, where the patterns are pre-stored in flash memory and then streamed to the DMD. The DMD pattern rates are shown in [Table](#page-18-3) 1 and depend on the desired bit depth.

The DLP9000XFLS DMD is controlled by the DLPC910 controller, where the DLPC910 is configured by the configuration data in the DLPR910. This chipset offers streaming 1-bit binary patterns to the DMD at speeds greater than 61 Gigabits per second (Gbps). The patterns are streamed from a customer designed applications processor into the DLPC910 input LVDS data interface. [Table](#page-18-4) 2 shows the pattern rates for the different DMD Reset Modes.

Table 1. DLP9000FLS Pattern Rates

(1) Pixel data rates are based on burst operating mode, maximum 400 binary patterns.

(2) Pattern rates are based on loading the entire DMD in global reset mode. Refer to the DLPC900 data sheet listed in [相关文档](#page-47-3) regarding operating modes.

Table 2. DLP9000XFLS Pattern Rates

(1) Refer to the DLPC910 data sheet in $\frac{H\cancel{\times} x}{H}$ for a description of the reset modes.

(2) Pixel data rates are based on continuous streaming.

(3) Increasing exposure periods may be necessary for a desired application but may decrease pattern rate.

(4) Global reset mode allows for continuous or pulsed illumination source.

(5) This reset mode typically requires pulsed illumination such as a laser or LED.

7.10 System Mounting Interface Loads

Figure 8. System Mounting Interface Loads

7.11 Micromirror Array Physical Characteristics

(1) Combined loads of the thermal and electrical interface areas in excess of Datum "A" load shall be evenly distributed outside the Datum *A* area (300 + 35 – Datum *A*).

(1) The structure and qualities of the border around the active array includes a band of partially functional micromirrors called the POM. These micromirrors are structurally and/or electrically prevented from tilting toward the bright or ON state, but still require an electrical bias to tilt toward OFF.

Refer to section *Micromirror Array Physical [Characteristics](#page-19-1)* table for M, N, and P specifications.

Figure 9. Micromirror Array Physical Characteristics

7.12 Micromirror Array Optical Characteristics

Refer to *Optical [Interface](#page-29-3) and System Image Quality* for important information.

(1) Measured relative to the plane formed by the overall micromirror array.

 (2) Additional variation exists between the micromirror array and the package datums.
(3) Represents the landed tilt angle variation relative to the nominal landed tilt angle.

- (3) Represents the landed tilt angle variation relative to the nominal landed tilt angle.
(4) Represents the variation that can occur between any two individual micromirrors. Represents the variation that can occur between any two individual micromirrors, located on the same device or located on different devices.
- (5) For some applications, it is critical to account for the micromirror tilt angle variation in the overall system optical design. With some system optical designs, the micromirror tilt angle variation within a device may result in perceivable non-uniformities in the light field reflected from the micromirror array. With some system optical designs, the micromirror tilt angle variation between devices may result in colorimetry variations, system efficiency variations or system contrast variations.
- (6) When the micromirror array is landed (not parked), the tilt direction of each individual micromirror is dictated by the binary contents of the CMOS memory cell associated with each individual micromirror. A binary value of 1 results in a micromirror landing in the ON State direction. A binary value of 0 results in a micromirror landing in the OFF State direction.
- (7) An out-of-specification micromirror is defined as a micromirror that is unable to transition between the two landed states within the specified Micromirror Switching Time.
- Micromirror crossover time is primarily a function of the natural response time of the micromirrors.
- (9) Performance as measured at the start of life.
- (10) Efficiency numbers assume 24-degree illumination angle, F/2.4 illumination and collection cones, uniform source spectrum, and uniform pupil illumination. Efficiency numbers assume 100% electronic mirror duty cycle and do not include optical overfill loss. Note that this number is specified under conditions described above and deviations from the specified conditions could result in decreased efficiency.

Refer to section *Micromirror Array Physical [Characteristics](#page-19-1)* table for M, N, and P specifications.

Figure 11. Micromirror Landed Orientation and Tilt

7.13 Optical and System Image Quality

Optimizing system optical performance and image quality strongly relate to optical system design parameter trades. Although it is not possible to anticipate every conceivable application, projector image quality and optical performance is contingent on compliance to the optical system operating conditions described in a) through c) below: a) Numerical Aperture and Stray Light Control. The angle defined by the numerical aperture of the illumination and projection optics at the DMD optical area should be the same. This angle should not exceed the nominal device mirror tilt angle unless appropriate apertures are added in the illumination and/or projection pupils to block out flat-state and stray light from the projection lens. The mirror tilt angle defines DMD capability to separate the "ON" optical path from any other light path, including undesirable flat-state specular reflections from the DMD window, DMD border structures, or other system surfaces near the DMD such as prism or lens surfaces. If the numerical aperture exceeds the mirror tilt angle, or if the projection numerical aperture angle is more than two degrees larger than the illumination numerical aperture angle, objectionable artifacts in the display's border and/or active area could occur. b) Pupil Match. TI's optical and image quality specifications assume that the exit pupil of the illumination optics is nominally centered within two degrees of the entrance pupil of the projection optics. Misalignment of pupils can create objectionable artifacts in the display's border and/or active area, which may require additional system apertures to control, especially if the numerical aperture of the system exceeds the pixel tilt angle. c) Illumination Overfill. Overfill light illuminating the area outside the active array can create artifacts from the mechanical features that surround the active array and other surface anomalies that may be visible on the screen. The illumination optical system should be designed to limit light flux incident anywhere outside the active array more than 20 pixels from the edge of the active array on all sides. Depending on the particular system's optical architecture and assembly tolerances, this amount of overfill light on the outside of the active array may still cause artifacts to still be visible. TI ASSUMES NO RESPONSIBILITY FOR IMAGE QUALITY ARTIFACTS OR DMD FAILURES CAUSED BY OPTICAL SYSTEM OPERATING CONDITIONS EXCEEDING LIMITS DESCRIBED ABOVE.

7.14 Window Characteristics

(1) Refer to *Window [Characteristics](#page-29-1) and Optics* for more information.

(2) For details regarding the size and location of the window aperture, refer to the package mechanical characteristics listed in the

Mechanical ICD in the Mechanical, Packaging, and Orderable Information section.

(3) Refer to the TI application report [DLPA031](http://www.ti.com/cn/lit/pdf/DLPA031), *Wavelength Transmittance Considerations for DMD Window*.

7.15 Chipset Component Usage Specification

The DMD is a component of one or more DLP® chipsets. Reliable function and operation of the DMD requires that it be used in conjunction with the other components of the applicable DLP® chipset, including those components that contain or implement TI DMD control technology. TI DMD control technology is the TI technology and devices for operating or controlling a DMD.

8 Parameter Measurement Information

The data sheet provides timing at the device pin. For output timing analysis, the tester pin electronics and its transmission line effects must be taken into account. [Figure](#page-23-1) 12 shows an equivalent test load circuit for the output under test. The load capacitance value stated is only for characterization and measurement of AC timing signals. This load capacitance value does not indicate the maximum load the device is capable of driving.

Timing reference loads are not intended as a precise representation of any particular system environment or depiction of the actual load presented by a production test. System designers should use IBIS or other simulation tools to correlate the timing reference load to a system environment. Refer to the *Application and [Implementation](#page-34-0)* section.

Figure 12. Test Load Circuit

9 Detailed Description

9.1 Overview

The DMD is a 0.9 inch diagonal spatial light modulator which consists of an array of highly reflective aluminum micromirrors. Pixel array size and square grid pixel arrangement are shown in [Figure](#page-20-0) 9.

The DMD is an electrical input, optical output micro-electrical-mechanical system (MEMS). The electrical interface is Low Voltage Differential Signaling (LVDS), Double Data Rate (DDR).

The DMD consists of a two-dimensional array of 1-bit CMOS memory cells. The array is organized in a grid of *M* memory cell columns by *N* memory cell rows. Refer to the *[Functional](#page-25-0) Block Diagram*.

The positive or negative deflection angle of the micromirrors can be individually controlled by changing the address voltage of underlying CMOS addressing circuitry and micromirror reset signals (MBRST).

Each cell of the *M × N* memory array drives its true and complement ('Q' and 'QB') data to two electrodes underlying one micromirror, one electrode on each side of the diagonal axis of rotation. Refer to *[Micromirror](#page-21-0) Array Optical [Characteristics](#page-21-0)*. The micromirrors are electrically tied to the micromirror reset signals (MBRST) and the micromirror array is divided into reset groups.

Electrostatic potentials between a micromirror and its memory data electrodes cause the micromirror to tilt toward the illumination source in a DLP projection system or away from it, thus reflecting its incident light into or out of an optical collection aperture. The positive (+) tilt angle state corresponds to an 'on' pixel, and the negative (–) tilt angle state corresponds to an 'off' pixel.

Refer to *Micromirror Array Optical [Characteristics](#page-21-0)* for the ± tilt angle specifications. Refer to *Pin [Configuration](#page-2-1) and [Functions](#page-2-1)* for more information on micromirror reset control.

9.2 Functional Block Diagram

Not to Scale. Details Omitted for Clarity. See Accompanying Notes in this Section.

For pin details on Channels A, B, C, and D, refer to *Pin [Configuration](#page-2-1) and Functions* and LVDS Interface section of *Timing [Requirements](#page-13-0)*.

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9.3 Feature Description

The DMD consists of 4096000 highly reflective, digitally switchable, micrometer-sized mirrors (micromirrors) organized in a two-dimensional orthogonal pixel array. Refer to [Figure](#page-20-0) 9 and [Figure](#page-27-0) 13.

Each aluminum micromirror is switchable between two discrete angular positions, –α and +α. The angular positions are measured relative to the micromirror array plane, which is parallel to the silicon substrate. Refer to *Micromirror Array Optical [Characteristics](#page-21-0)* and [Figure](#page-28-0) 14.

The parked position of the micromirror is not a latched position and is therefore not necessarily perfectly parallel to the array plane. Individual micromirror flat state angular positions may vary. Tilt direction of the micromirror is perpendicular to the hinge-axis. The on-state landed position is directed toward the left-top edge of the package, as shown in [Figure](#page-27-0) 13.

Each individual micromirror is positioned over a corresponding CMOS memory cell. The angular position of a specific micromirror is determined by the binary state (logic 0 or 1) of the corresponding CMOS memory cell contents, after the mirror clocking pulse is applied. The angular position $(-\alpha$ and $+\alpha)$ of the individual micromirrors changes synchronously with a micromirror clocking pulse, rather than being coincident with the CMOS memory cell data update.

Writing logic 1 into a memory cell followed by a mirror clocking pulse results in the corresponding micromirror switching to a +α position. Writing logic 0 into a memory cell followed by a mirror clocking pulse results in the corresponding micromirror switching to a – α position.

Updating the angular position of the micromirror array consists of two steps. First, update the contents of the CMOS memory. Second, apply a micromirror reset (also referred as Mirror Clocking Pulse) to all or a portion of the micromirror array (depending upon the configuration of the system). Micromirror reset pulses are generated internally by the DMD, with application of the pulses being coordinated by the DLPC900 or the DLPC910 digital controller.

For more information, refer to the TI application report [DLPA008](http://www.ti.com/cn/lit/pdf/DLPA008), *DMD101: Introduction to Digital Micromirror Device (DMD) Technology*.

EXAS ISTRUMENTS

Feature Description (continued)

Feature Description (continued)

Micromirror States: On, Off, Flat

9.4 Device Functional Modes

9.4.1 DLP9000FLS

The DLP9000FLS DMD is controlled by two DLPC900 digital controllers. These controllers have two modes of operation. The first is Video mode where the video source is displayed on the DMD. The second is Pattern mode, where the patterns are pre-stored in flash memory and then streamed to the DMD. The resulting DMD pattern rate depends on which mode and bit-depth is selected. For more information, refer to the DLPC900 data sheet listed under [相关文档](#page-47-3).

9.4.2 DLP9000XFLS

The DLP9000XFLS DMD is controlled by one DLPC910 digital controller. The digital controller offers high speed streaming mode where 1-bit binary patterns are accepted at the LVDS interface input, and then streamed to the DMD. To ensure reliable operation, the DLP9000XFLS must always be used with the DLPC910. For more information, refer to the DLPC910 data sheet listed under [相关文档](#page-47-3).

9.5 Window Characteristics and Optics

NOTE

TI assumes no responsibility for image quality artifacts or DMD failures caused by optical system operating conditions exceeding limits described previously.

9.5.1 Optical Interface and System Image Quality

TI assumes no responsibility for end-equipment optical performance. Achieving the desired end-equipment optical performance involves making trade-offs between numerous component and system design parameters. Optimizing system optical performance and image quality strongly relate to optical system design parameter trades. Although it is not possible to anticipate every conceivable application, projector image quality and optical performance is contingent on compliance to the optical system operating conditions described in the following sections.

9.5.2 Numerical Aperture and Stray Light Control

The angle defined by the numerical aperture of the illumination and projection optics at the DMD optical area should be the same. This angle should not exceed the nominal device mirror tilt angle unless appropriate apertures are added in the illumination and/or projection pupils to block out flat-state and stray light from the projection lens. The mirror tilt angle defines DMD capability to separate the "ON" optical path from any other light path, including undesirable flat-state specular reflections from the DMD window, DMD border structures, or other system surfaces near the DMD such as prism or lens surfaces. If the numerical aperture exceeds the mirror tilt angle, or if the projection numerical aperture angle is more than two degrees larger than the illumination numerical aperture angle, objectionable artifacts in the display's border and/or active area could occur.

9.5.3 Pupil Match

TI's optical and image quality specifications assume that the exit pupil of the illumination optics is nominally centered within 2° (two degrees) of the entrance pupil of the projection optics. Misalignment of pupils can create objectionable artifacts in the display's border and/or active area, which may require additional system apertures to control, especially if the numerical aperture of the system exceeds the pixel tilt angle.

9.5.4 Illumination Overfill

The active area of the device is surrounded by an aperture on the inside DMD window surface that masks structures of the DMD device assembly from normal view. The aperture is sized to anticipate several optical operating conditions. Overfill light illuminating the window aperture can create artifacts from the edge of the window aperture opening and other surface anomalies that may be visible on the screen. The illumination optical system should be designed to limit light flux incident anywhere on the window aperture from exceeding approximately 10% of the average flux level in the active area. Depending on the particular system's optical architecture, overfill light may have to be further reduced below the suggested 10% level in order to be acceptable.

9.6 Micromirror Array Temperature Calculation

Figure 15. DMD Thermal Test Points

Micromirror array temperature can be computed analytically from measurement points on the outside of the package, the ceramic package thermal resistance, the electrical power dissipation, and the illumination heat load. The relationship between micromirror array temperature and the reference ceramic temperature is provided by the following equations:

Where:

 T_{ARRAY} = Computed micromirror array temperature (°C)

 $T_{CERAMIC}$ = Measured ceramic temperature (°C), TP1 location in [Figure](#page-30-1) 15

 $R_{ARRAY-TO-CERAMIC}$ = DMD package thermal resistance from micromirror array to outside ceramic (°C/W) specified in *Thermal [Information](#page-12-0)*

QARRAY = Total DMD power; electrical, specified in *Electrical [Characteristics](#page-12-1)*, plus absorbed (calculated) (W) QELECTRICAL = DMD electrical power dissipation (W), specified in *Electrical [Characteristics](#page-12-1)*

 C_{L2W} = Conversion constant for screen lumens to absorbed optical power on the DMD (W/lm) specified below

SL = Measured ANSI screen lumens (lm)

Electrical power dissipation of the DMD is variable and depends on the voltages, data rates and operating frequencies. Absorbed optical power from the illumination source is variable and depends on the operating state of the micromirrors and the intensity of the light source. Equations shown above produce a total projection efficiency through the projection lens from DMD to the screen of 87%.

The conversion constant CL2W is based on the DMD micromirror array characteristics. It assumes a spectral efficiency of 300 lm/W for the projected light and illumination distribution of 83.7% on the DMD active array, and 16.3% on the DMD array border and window aperture. The conversion constant is calculated to be 0.00293 W/lm.

Sample Calculation for typical projection application:

T_{CERAMIC} = 55°C, assumed system measurement; refer to *[Recommended](#page-10-2) Operating Conditions* regarding specific limits.

SL = 2000 lm

QELECTRICAL = 9.87W for the DLP9000FLS (refer to the power specifications in *Electrical [Characteristics](#page-12-1)*) $C_{L2W} = 0.00293$ W/lm

Micromirror Array Temperature Calculation (continued)

 Q_{ARRAY} = 9.87 W + (0.00293 W/lm \times 2000 lm) = 15.73 W $T_{\text{ARRAY}} = 55^{\circ}\text{C} + (15.73 \text{ W} \times 0.5 \text{ }^{\circ}\text{C/W}) = 62.87^{\circ}\text{C}$

9.7 Micromirror Landed-On/Landed-Off Duty Cycle

9.7.1 Definition of Micromirror Landed-On/Landed-Off Duty Cycle

The micromirror landed-on/landed-off duty cycle (landed duty cycle) denotes the amount of time (as a percentage) that an individual micromirror is landed in the On–state versus the amount of time the same micromirror is landed in the Off–state.

As an example, a landed duty cycle of 100/0 indicates that the referenced pixel is in the On-state 100% of the time (and in the Off-state 0% of the time); whereas 0/100 would indicate that the pixel is in the Off-state 100% of the time. Likewise, 50/50 indicates that the pixel is On 50% of the time and Off 50% of the time.

Note that when assessing landed duty cycle, the time spent switching from one state (ON or OFF) to the other state (OFF or ON) is considered negligible and is thus ignored.

Since a micromirror can only be landed in one state or the other (On or Off), the two numbers (percentages) always add to 100.

9.7.2 Landed Duty Cycle and Useful Life of the DMD

Knowing the long-term average landed duty cycle (of the end product or application) is important because subjecting all (or a portion) of the DMD's micromirror array (also called the active array) to an asymmetric landed duty cycle for a prolonged period of time can reduce the DMD's usable life.

Note that it is the symmetry/asymmetry of the landed duty cycle that is of relevance. The symmetry of the landed duty cycle is determined by how close the two numbers (percentages) are to being equal. For example, a landed duty cycle of 50/50 is perfectly symmetrical whereas a landed duty cycle of 100/0 or 0/100 is perfectly asymmetrical.

9.7.3 Landed Duty Cycle and Operational DMD Temperature

Operational DMD Temperature and Landed Duty Cycle interact to affect the DMD's usable life, and this interaction can be exploited to reduce the impact that an asymmetrical Landed Duty Cycle has on the DMD's usable life. This is quantified in the de-rating curve shown in [Figure](#page-32-0) 16. The importance of this curve is that:

- All points along this curve represent the same usable life.
- All points above this curve represent lower usable life (and the further away from the curve, the lower the usable life).
- All points below this curve represent higher usable life (and the further away from the curve, the higher the usable life).

In practice, this curve specifies the Maximum Operating DMD Temperature that the DMD should be operated at for a give long-term average Landed Duty Cycle.

Micromirror Landed-On/Landed-Off Duty Cycle (continued)

9.7.4 Estimating the Long-Term Average Landed Duty Cycle of a Product or Application

During a given period of time, the Landed Duty Cycle of a given pixel follows from the image content being displayed by that pixel.

For example, in the simplest case, when displaying pure-white on a given pixel for a given time period, that pixel will experience a 100/0 Landed Duty Cycle during that time period. Likewise, when displaying pure-black, the pixel will experience a 0/100 Landed Duty Cycle.

Between the two extremes (ignoring for the moment color and any image processing that may be applied to an incoming image), the Landed Duty Cycle tracks one-to-one with the gray scale value, as shown in [Table](#page-32-1) 3.

Accounting for color rendition (but still ignoring image processing) requires knowing both the color intensity (from 0% to 100%) for each constituent primary color (red, green, and/or blue) for the given pixel as well as the color cycle time for each primary color, where "color cycle time" is the total percentage of the frame time that a given primary must be displayed in order to achieve the desired white point.

During a given period of time, the landed duty cycle of a given pixel can be calculated as follows:

Landed Duty Cycle = (Red_Cycle_% x Red_Scale_Value) + (Green_Cycle_% x Green_Scale_Value) + (Blue_Cycle_% × Blue_Scale_Value)

Where:

Red_Cycle_%, Green_Cycle_%, and Blue_Cycle_%, represent the percentage of the frame time that Red, Green, and Blue are displayed (respectively) to achieve the desired white point.

For example, assume that the red, green and blue color cycle times are 50%, 20%, and 30% respectively (in order to achieve the desired white point), then the Landed Duty Cycle for various combinations of red, green, blue color intensities would be as shown in [Table](#page-33-0) 4.

Table 4. Example Landed Duty Cycle for Full-Color

10 Application and Implementation

NOTE

Information in the following applications sections is not part of the TI component specification, and TI does not warrant its accuracy or completeness. TI's customers are responsible for determining suitability of components for their purposes. Customers should validate and test their design implementation to confirm system functionality.

10.1 Application Information

The DLP9000FLS DMD is controlled by two DLPC900 controllers. This chipset offers two modes of operation. The first is Video mode where the video source is displayed on the DMD. The second is Pattern mode, where the patterns are pre-stored in flash memory and then streamed to the DMD. The allowed DMD pattern rate depends on which mode and bit-depth is selected.

The DLP9000XFLS DMD is controlled by the DLPC910 controller, where the DLPC910 is configured by the program content in the DLPR910. This chipset offers streaming 1-bit binary patterns to the DMD at speeds greater than 61 Gigabits per second (Gbps). The patterns are streamed from an customer designed processor into the DLPC910 LVDS input data interface.

Both the DLP9000FLS and the DLP9000XFLS provide solutions for many varied applications including structured light, 3-D printing, video projection, and high speed lithography. The DMD is a spatial light modulator, which reflects incoming light from an illumination source to one of two directions, with the primary direction being into a projection or collection optic. Each application is derived primarily from the optical architecture of the system and the format of the data being used.

10.2 Typical Applications

10.2.1 Typical Application using DLP9000FLS

A typical embedded system application using two DLPC900 controllers and a DLP9000FLS DMD is shown in [Figure](#page-35-0) 17. In this configuration, the DLPC900 controller supports a 24-bit parallel RGB input, typical of LCD interfaces, from an external source or processor. The 24-bit parallel data must be split between a left half and a right half, each half between the two controllers. The external processor must format each half to consist of 1280x1600 plus any horizontal and vertical blanking at half the pixel clock rate. This system configuration supports still and motion video as well as sequential pattern modes. For more information, refer to the DLPC900 digital controller data sheet listed under [相关文档](#page-47-3).

Typical Applications (continued)

Figure 17. DLP9000FLS Typical Application Schematic

10.2.1.1 Design Requirements

Detailed design requirements are located in the DLPC900 or the DLPC910 digital controller data sheets. Refer to the data sheets listed under [相关文档](#page-47-3).

10.2.1.2 Detailed Design Procedure

Reference Design material exists for systems using either the DLP9000FLS or the DLP9000XFLS DMD with their respective Controllers. This reference material includes reference board schematics, PCB layouts, and Bills of Materials. Layout guidelines for boards utilizing these controllers and DMDs can be found in the respective DLPC900 or DLPC910 Controller data sheets. For more information, please refer to the individual controller data sheets listed under [相关文档](#page-47-3).

10.2.2 Typical Application using DLP9000XFLS

Direct-write digital imaging is regularly used in high-end lithography printing. This mask-less technology offers a continuous run of printing by changing the digitally created patterns without stopping the imaging head. [Figure](#page-36-0) 18shows a system where a DLPC910 digital controller is coupled with the DLP9000XFLS DMD. This system offers an ideal back-end imager that takes in digital images at 2560 x 1600 in resolution to achieve speeds of more than 61 Gbps. For more information, refer to the DLPC910 digital controller data sheet listed under [相关文档](#page-47-3).

Typical Applications (continued)

Figure 18. DLP9000XFLS Typical Application Schematic

11 Power Supply Recommendations

11.1 DMD Power Supply Requirements

The following power supplies are all required to operate the DMD: VCC, VCCI, VOFFSET, VBIAS, and VRESET. VSS must also be connected. DMD power-up and power-down sequencing is strictly controlled by the DLPC900 or DLPC910 Controllers within their associated reference designs.

CAUTION

For reliable operation of the DMD, the following power supply sequencing requirements must be followed. Failure to adhere to the prescribed power-up and power-down procedures may affect device reliability. VCC, VCCI, VOFFSET, VBIAS, and VRESET power supplies have to be coordinated during power-up and powerdown operations. VSS must also be connected. Failure to meet any of the below requirements will result in a significant reduction in the DMD's reliability and lifetime. Refer to [Figure](#page-38-0) 19.

11.2 DMD Power Supply Power-Up Procedure

- During power-up, VCC and VCCI must always start and settle before VOFFSET, VBIAS, and VRESET voltages are applied to the DMD.
- During power-up, it is a strict requirement that the delta between VBIAS and VOFFSET must be within the specified limit shown in *[Recommended](#page-10-2) Operating Conditions. During power-up, VBIAS does not have to start after VOFFSET.*
- During power-up, there is no requirement for the relative timing of VRESET with respect to VOFFSET and VBIAS.
- Power supply slew rates requirements during power-up are flexible, provided that the transient voltage levels follow the requirements listed in *Absolute [Maximum](#page-9-1) Ratings*, in *[Recommended](#page-10-2) Operating Conditions*, and in [Figure](#page-38-0) 19.
- During power-up, LVCMOS input pins shall not be driven high until after VCC and VCCI have settled at operating voltages listed in *[Recommended](#page-10-2) Operating Conditions*.

11.3 DMD Power Supply Power-Down Procedure

- During power-down, VCC and VCCI must be supplied until after VBIAS, VRESET, and VOFFSET are discharged to within the specified limit of ground. Refer to [Table](#page-39-0) 5.
- During power-down, it is a strict requirement that the delta between VBIAS and VOFFSET must be within the specified limit shown in *[Recommended](#page-10-2) Operating Conditions*. During power-down, it is not mandatory to stop driving VBIAS prior to VOFFSET.
- During power-down, there is no requirement for the relative timing of VRESET with respect to VOFFSET and VBIAS.
- Power supply slew rates during power-down are flexible, provided that the transient voltage levels follow the requirements listed in *Absolute [Maximum](#page-9-1) Ratings, in [Recommended](#page-10-2) Operating Conditions, and in* [Figure](#page-38-0) 19.
- During power-down, LVCMOS input pins must be less than specified in *[Recommended](#page-10-2) Operating Conditions.*

DMD Power Supply Power-Down Procedure (continued)

- 1. To prevent excess current, the supply voltage delta |VBIAS – VOFFSET| must be less than specified in *[Recommended](#page-10-2) Operating Conditions. OEMs may find that the most reliable way to ensure this is to power VOFFSET prior to VBIAS during power-up and to remove VBIAS prior to VOFFSET during power-down.*
- 2. During power-up, the LVDS signals are less than the input differential voltage (VID) maximum specified in

DMD Power Supply Power-Down Procedure (continued)

[Recommended](#page-10-2) Operating Conditions. During power-down, LVDS signals are less than the high level input voltage (VIH) maximum specified in *[Recommended](#page-10-2) Operating Conditions*.

- 3. When system power is interrupted, the DLPC900 and the DLPC910 controllers initiate a hardware powerdown that activates PWRDNZ and disables VBIAS, VRESET and VOFFSET after the micromirror park sequence. Software power-down disables VBIAS, VRESET, and VOFFSET after the micromirror park sequence through software control. For either case, enable signals EN_BIAS, EN_OFFSET, and EN_RESET are used to disable VBIAS, VOFFSET, and VRESET, respectfully.
- 4. Refer to [Table](#page-39-0) 5.
- 5. Figure not to scale. Details have been omitted for clarity. Refer to *[Recommended](#page-10-2) Operating Conditions*.

Table 5. DMD Power-Down Sequence Requirements

12 Layout

12.1 Layout Guidelines

Each chipset provides a solution for many applications including structured light and video projection. This section provides layout guidelines for the DMD.

12.1.1 General PCB Recommendations

The PCB shall be designed to IPC2221 and IPC2222, Class 2, Type Z, at level B producibility and built to IPC6011 and IPC6012, class 2. The PCB board thickness to be 0.062 inches ±10%, using a dielectric material with a low Loss-Tangent, for example: Hitachi 679gs or equivalent.

Two-ounce copper planes are recommended in the PCB design in order to achieve needed thermal connectivity. Refer to the digital controller data sheets listed under [相关文档](#page-47-3) regarding DMD Interface Considerations.

High-speed interface waveform quality and timing on the digital controllers (that is, the LVDS DMD interface) is dependent on the following factors:

- Total length of the interconnect system
- Spacing between traces
- Characteristic impedance
- Etch losses
- How well matched the lengths are across the interface

Thus, ensuring positive timing margin requires attention to many factors.

As an example, DMD interface system timing margin can be calculated as follows:

- Setup Margin = (controller output setup) (DMD input setup) (PCB routing mismatch) (PCB SI degradation)
- Hold-time Margin = (controller output hold) (DMD input hold) (PCB routing mismatch) (PCB SI degradation)

The PCB SI degradation is the signal integrity degradation due to PCB affects which includes such things as simultaneously switching output (SSO) noise, crosstalk, and inter-symbol-interference (ISI) noise.

Both the DLPC910 and the DLPC900 I/O timing parameters can be found in their respective data sheets. Similarly, PCB routing mismatch can be easily budgeted and met via controlled PCB routing. However, PCB SI degradation is not as easy to determine.

In an attempt to minimize the signal integrity analysis that would otherwise be required, the following PCB design guidelines provide a reference of an interconnect system that satisfies both waveform quality and timing requirements (accounting for both PCB routing mismatch and PCB SI degradation). Deviation from these recommendations should be confirmed with PCB signal integrity analysis or lab measurements.

12.1.2 Power Planes

Signal routing is NOT allowed on the power and ground planes. All device pin and via connections to this plane shall use a thermal relief with a minimum of four spokes. The power plane shall clear the edge of the PCB by 0.2".

Prior to routing, vias connecting all digital ground layers (GND) should be placed around the edge of the rigid PWB regions 0.025" from the board edges with a 0.100" spacing. It is also desirable to have all internal digital ground (GND) planes connected together in as many places as possible. If possible, all internal ground planes should be connected together with a minimum distance between connections of 0.5". Extra vias are not required if there are sufficient ground vias due to normal ground connections of devices. NOTE: All signal routing and signal vias should be inside the perimeter ring of ground vias.

Power and Ground pins of each component shall be connected to the power and ground planes with one via for each pin. Trace lengths for component power and ground pins should be minimized (ideally, less than 0.100"). Unused or spare device pins that are connected to power or ground may be connected together with a single via to power or ground. Ground plane slots are NOT allowed.

Route VOFFSET, VBIAS, and VRESET as a wide trace >20 mils (wider if space allows) with 20 mils spacing.

Layout Guidelines (continued)

12.1.3 LVDS Signals

The LVDS signals shall be first. Each pair of differential signals must be routed together at a constant separation such that constant differential impedance (as in section *Board Stack and Impedance [Requirements](#page-42-1)*) is maintained throughout the length. Avoid sharp turns and layer switching while keeping lengths to a minimum. The distance from one pair of differential signals to another shall be at least 2 times the distance within the pair.

12.1.4 Critical Signals

The critical signals on the board must be hand routed in the order specified below. In case of length matching requirements, the longer signals should be routed in a serpentine fashion, keeping the number of turns to a minimum and the turn angles no sharper than 45 degrees. Avoid routing long trace all around the PCB.

12.1.5 Flex Connector Plating

Plate all the pad area on top layer of flex connection with a minimum of 35 and maximum 50 micro-inches of electrolytic hard gold over a minimum of 150 micro-inches of electrolytic nickel.

12.1.6 Device Placement

Unless otherwise specified, all major components should be placed on top layer. Small components such as ceramic, non-polarized capacitors, resistors and resistor networks can be placed on bottom layer. All high frequency de-coupling capacitors for the ICs shall be placed near the parts. Distribute the capacitors evenly around the IC and locate them as close to the device's power pins as possible (preferably with no vias). In the case where an IC has multiple de-coupling capacitors with different values, alternate the values of those that are side by side as much as possible and place the smaller value capacitor closer to the device.

12.1.7 Device Orientation

It is desirable to have all polarized capacitors oriented with their positive terminals in the same direction. If polarized capacitors are oriented both horizontally and vertically, then all horizontal capacitors should be oriented with the "+" terminal the same direction and likewise for the vertically oriented ones.

12.1.8 Fiducials

Fiducials for automatic component insertion should be placed on the board according to the following guidelines or on recommendation from manufacturer:

- Fiducials for optical auto insertion alignment shall be placed on three corners of both sides of the PWB.
- Fiducials shall also be placed in the center of the land patterns for fine pitch components (lead spacing $< 0.05"$).
- Fiducials should be 0.050 inch copper with 0.100 inch cutout (antipad).

12.2 Layout Example

12.2.1 Board Stack and Impedance Requirements

Refer to [Figure](#page-43-0) 20 regarding guidance on the parameters.

PCB design:

PCB stack-up:

Reference plane 1 is assumed to be a ground plane for proper return path.

Layout Example (continued)

Figure 20. PCB Stack Geometries

Layout Example (continued)

(1) Spacing may vary to maintain differential impedance requirements

Table 8. DMD Interface Specific Routing

Number of layer changes:

- Single-ended signals: Minimize
- Differential signals: Individual differential pairs can be routed on different layers but the signals of a given pair should not change layers.

(1) Max signal routing length includes escape routing.

Stubs: Stubs should be avoided.

Termination Requirements: DMD interface: None – The DMD receiver is differentially terminated to 100 Ω internally.

Connector (DMD-LVDS interface bus only):

High-speed connectors that meet the following requirements should be used:

- Differential crosstalk:<5%
- Differential impedance: 75 to 125 Ω

Routing requirements for right-angle connectors: When using right-angle connectors, P-N pairs should be routed in the same row to minimize delay mismatch. When using right-angle connectors, propagation delay difference for each row should be accounted for on associated PCB etch lengths. Voltage or low frequency signals should be routed on the outer layers. Signal trace corners shall be no sharper than 45 degrees. Adjacent signal layers shall have the predominant traces routed orthogonal to each other.

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[DLP9000](http://www.ti.com.cn/product/cn/dlp9000?qgpn=dlp9000)

13 器件和文档支持

13.1 器件支持

13.1.1 器件处理

DMD 上的所有外部信号均不受静电放电的损害,经测试符合 JESD22-A114-B 静电放电 (ESD) 敏感度测试人体模 型 (HBM)。

封装引脚类型	电压(最大值)	单位
输入	2000	
输出	2000	
VCC	2000	
VCCI	2000	
VOFFSET	2000	
VBIAS	2000	
VRESET	2000	
所有 MBRST	2000	

表 **10. DMD ESD** 保护限值

所有 CMOS 器件均需遵循适当的静电放电 (ESD) 处理程序。请参见图纸 2504641 DMD 处理规范,了解关于对 DMD 实施 ESD 保护以及保护 DMD 玻璃和电触点的预防措施。请参见图纸 2504640 DMD 玻璃清洁程序,掌握 DMD 玻璃的正确清洁方式,避免损坏玻璃表面上的抗反射涂层。

13.1.2 器件命名规则

图 [21](#page-46-2) 提供了读取任一 DLP 器件完整器件名称的图例。

图 **21.** 器件命名规则

13.1.3 器件标记

器件标记将包括可读信息和一个二维矩阵码。图 [22](#page-47-4) 中显示了可读信息。二维矩阵码是一个字母数字字符串,其中 包含 DMD 部件号、序列号的第 1 部分和序列号的第 2 部分。DMD 序列号(第 1 部分)的首字符为制造年份。 DMD 序列号(第 1 部分)的第二个字符为制造月份。DMD 序列号(第 2 部分)的最后一个字符为偏置电压二进 制字母。

[DLP9000](http://www.ti.com.cn/product/cn/dlp9000?qgpn=dlp9000) ZHCSD19A –SEPTEMBER 2014–REVISED OCTOBER 2015 **www.ti.com.cn**

13.2 文档支持

13.2.1 相关文档

以下文档包含使用 DLP9000 系列器件的更多信息:

- 《DLPC900 数字控制器数据表》(文献编号:[DLPS037](http://www.ti.com/cn/lit/pdf/DLPS037))
- 《DLPC900 软件编程人员指南》(文献编号: [DLPU018](http://www.ti.com/cn/lit/pdf/DLPU018))
- 《DLPC910 数字控制器数据表》(文献编号:[DLPS064](http://www.ti.com/cn/lit/pdf/DLPS064))
- 《DLPR910 配置 PROM 数据表》(文献编号: [DLPS065](http://www.ti.com/cn/lit/pdf/DLPS065))

13.3 社区资源

The following links connect to TI community resources. Linked contents are provided "AS IS" by the respective contributors. They do not constitute TI specifications and do not necessarily reflect TI's views; see TI's [Terms](http://www.ti.com/corp/docs/legal/termsofuse.shtml) of [Use.](http://www.ti.com/corp/docs/legal/termsofuse.shtml)

TI E2E™ Online [Community](http://e2e.ti.com) *TI's Engineer-to-Engineer (E2E) Community.* Created to foster collaboration among engineers. At e2e.ti.com, you can ask questions, share knowledge, explore ideas and help solve problems with fellow engineers.

Design [Support](http://support.ti.com/) *TI's Design Support* Quickly find helpful E2E forums along with design support tools and contact information for technical support.

13.4 商标

E2E is a trademark of Texas Instruments. All other trademarks are the property of their respective owners.

13.5 静电放电警告

这些装置包含有限的内置 ESD 保护。 存储或装卸时, 应将导线一起截短或将装置放置于导电泡棉中, 以防止 MOS 门极遭受静电损

13.6 Glossary

[SLYZ022](http://www.ti.com/cn/lit/pdf/SLYZ022) — *TI Glossary*.

This glossary lists and explains terms, acronyms, and definitions.

14 机械、封装和可订购信息

以下页中包括机械、封装和可订购信息。这些信息是针对指定器件可提供的最新数据。这些数据会在无通知且不对 本文档进行修订的情况下发生改变。欲获得该数据表的浏览器版本,请查阅左侧的导航栏

14.1 热特性

要使 DMD 达到最佳性能, 需要对 DMD 外壳的最高温度、有源阵列中任一微镜的最高温度以及封装上任意两点间 的温度梯度和封装内的温度梯度进行适当管理。

关于适用的温度限值,请参见*Absolute [Maximum](#page-9-1) Ratings*和*[Recommended](#page-10-2) Operating Conditions*。

14.2 封装热阻

DMD 经设计可将吸收和消散的热量传递回 FLS 系列封装,然后通过适当的热管理系统排出。该热管理系统必须能 够将封装维持在热测试点位置上指定的工作温度范围内(请参见[Figure](#page-30-1) 15 或*Micromirror Array [Temperature](#page-30-0) [Calculation](#page-30-0)*)。DMD 上的总体热负载通常由有源区域吸收的入射光驱动,不过可能还会有一部分来自窗口孔隙吸 收的光能、阵列的电气功耗以及寄生发热。有关热阻的信息,请参见*Thermal [Information](#page-12-0)*。

14.3 外壳温度

可以直接测量 DMD 外壳的温度。为确保测量结果的一致性,定义了一个热测试点位置,如[Figure](#page-30-1) 15 和 *Micromirror Array [Temperature](#page-30-0) Calculation*所示。

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www.ti.com 21-Feb-2018

PACKAGING INFORMATION

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⁽²⁾ RoHS: TI defines "RoHS" to mean semiconductor products that are compliant with the current EU RoHS requirements for all 10 RoHS substances, including the requirement that RoHS substance do not exceed 0.1% by weight in homogeneous materials. Where designed to be soldered at high temperatures. "RoHS" products are suitable for use in specified lead-free processes. TI may reference these types of products as "Pb-Free".

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(3) MSL, Peak Temp. - The Moisture Sensitivity Level rating according to the JEDEC industry standard classifications, and peak solder temperature.

(4) There may be additional marking, which relates to the logo, the lot trace code information, or the environmental category on the device.

(5) Multiple Device Markings will be inside parentheses. Only one Device Marking contained in parentheses and separated by a "~" will appear on a device. If a line is indented then it is a continuation of the previous line and the two combined represent the entire Device Marking for that device.

⁽⁶⁾ Lead/Ball Finish - Orderable Devices may have multiple material finish options. Finish options are separated by a vertical ruled line. Lead/Ball Finish values may wrap to two lines if the finish value exceeds the maximum column width.

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